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RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE REQUESTED
GROUP 2822

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IFW

Attorney Docket
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DO NOT ENTER
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8-4-04

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

CONFIRMATION NO.: 4442

In re Applicants: Hitoshi KATO, et al.

Serial No. : 10/066,627

Filed : February 6, 2002

Art Unit : 2822

Examiner : Maria F. Guerrero

For : PRECLEANING METHOD OF PRECLEANING A SILICON
NITRIDE FILM FORMING SYSTEM (AS AMENDED)

AMENDMENT IN RESPONSE TO FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed April 26, 2004, please amend the above-identified application as set forth below and consider the following remarks.